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What Is Claimed Is:

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1. An electro-static chuck with non-sintered aluminum nitride (AlN) comprising a coating layer of aluminum nitride as a dielectric of the electrostatic chuck.

- The electro-static chuck according to claim
 in which the coating layer of aluminum nitride is
 formed by depositing aluminum nitride powder by cold spray coating.
 - 3. The electro-static chuck according to claim 1, in which the electro-static chuck comprises:
 - a substrate formed of aluminum alloy, copper, copper alloy or ceramic;
 - a first aluminum nitride (AlN) layer formed on the substrate by cold spray coating;
- an electrode formed with a separation of a 20 distance from the circumference of the first aluminum nitride to the center on the first aluminum nitride (AlN) layer; and
- a second aluminum nitride (AlN) layer formed by cold spray coating to cover the whole of the electrode and the separation.
 - 4. The electro-static chuck according to claim 3, in which the first aluminum nitride layer has a thickness of 0.2 to 1.5 mm, the electrode has a thickness of 0.01 to 0.5 mm, and the second aluminum nitride layer has a thickness of 0.05 to 1 mm.
 - 5. A method for preparing an electro-static chuck with non-sintered aluminum nitride (AlN)

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comprising coating aluminum nitride as a dielectric on the electro-static chuck.

- 6. The method according to claim 5, in which the coating of aluminum nitride is performed by depositing aluminum nitride powder by cold spray coating.
- 7. The method according to claim 5, which 10 comprises:
 - a step for forming a first layer, in which aluminum nitride powder is deposited on a substrate by cold spray coating to form a first aluminum nitride layer as an insulating layer;
- a step for forming a second layer, in which conductive powder is deposited on the first layer by cold spray coating to form an electrode with a separation of a distance from the circumference of the first layer to the center; and
- a step for forming a third layer, in which aluminum nitride powder is deposited on the second layer and the separation by cold spray coating to form an aluminum nitride layer.
- 8. The method according to any one of claims 5 to 7, in which the cold spray coating is performed at a gas temperature of 400 to 500°C, a gas pressure of 3 to 7 kgf/cm, and a distance between the nozzle and the substrate of 5 to 50 mm.

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9. The method according to any one of claims 5 to 7, in which the aluminum nitride powder is combined with 10 to 30% by weight of polyimide,

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glass resin, polyvinyl alcohol or a mixture thereof, and pulverized.

- 10. The method according to claim 9, in which the pulverized mixture powder is screened to obtain a predetermined size.
- 11. The method according to claim 7, in which the first layer has a thickness of 0.2 to 1.5 mm, the second layer has a thickness of 0.01 to 0.5 mm, and the third layer has a thickness of 0.05 to 1 mm.
- 12. The method of claim 7, which further comprises, after the step for forming the third 15 layer:
 - a step for curing the electro-static chuck after completion of the coating and leveling the surface; and
- a step for forming auxiliary openings on the 20 chuck after completion of the curing.
 - 13. The method according to claim 12, in which the curing is performed at a temperature of 100 to 500° C.

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14. An electro-static chuck with non-sintered aluminum nitride (AlN) prepared by the method according to any one of claims 5 to 7, which has a dielectric constant of at least 8, measured at a frequency of 100 KHz to 1 MHz and an electrostatic force of at least 150 gf/cm, when a voltage of 500 V is applied.